



PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Stefan Peter Hau-Riege

Docket No.: IL-11154

Serial No.: 10/783,520

Group Art Unit: 2877

Filed : February 20, 2004

Examiner: S. Nguyen

For : Method For Characterizing Mask Defects Using  
Image Reconstruction From X-Ray Diffraction Patterns

AMENDMENT

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action mailed June 26, 2006, please amend the  
above-referenced application as follows: